

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Seiyo NAKASHIMA, et al.

Serial No.: 09/816,643

Filed:

March 23, 2001

For: SUBSTRATE PROCESSING APPARATUS AND SUBSTRATE PROCESSING METHOD

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents Washington, D.C. 20231

Dear Sir:

Examiner: Timothy H. Meeks

1762

Art Unit:

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed

Commissioner for Patents Washington D.C. 20231, on

August 8, 2002 Date of Deposit

Kimberly Yee Name

08/08/02 Date

Signature

In response to the Restriction Requirement dated July 26, 2002, Applicants, without traverse, elect for prosecution the claims of Group I, Claims 1-9. If there are any fees in connection with the filing of this response, please charge the fees to our Deposit Account No. 50-1314.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

Date: August 8, 2002

Registration No. 47,771

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